CONTENTS

For	warding Certificate	i
Cer	tificate of Approval	ii
Dec	elaration	iii
Ack	nowledgement	viii
A·bs	tract	ix
List	of Table	x
List	of Figure	xiii
Nor	nenclature	xvi
1.	Introduction	1-10
	1.1 Introduction	1
	1.2 The Sun and Its Spectrum	2
	1.2 Status of solar Power	4
	1.3 Solar Cell Efficiency and Some Related Issues	6
	1.4Layout of Report	9
2.	Literature Review	11-35
	2.1 Introduction	11
	2.2Solar Cell and Its Resistive Losses	13
	2.3Front Side Metallization of c-Si Solar Cells	17
	2.3.1 Screen Printing	18
	2.3.2 Laser Micro-sintering	21
	2.3.3 Light Induced Plating	23
	2.3.4 Ni/Cu Metallization	24
	2.3.5 Evaporated Ti/Pd/Ag Contact	28
	2.3.6 Metal Aerosol Jet Printing	31
	2.4 Effect of Light on Electroless Plating	33
	2.5 Objective of the Work	35

3.	Experimental Work	36-39
	3.1 Preparation of Sample	36
	3.2 Set up for light and dark Condition	37
	3.3 Bath Preparation and Experimental Procedure	39
4.	Results and Discussion	41-60
	4.1SEM and EDS	41
	4.1.1 Surface Morphology of Without Deposited Sample	42
	4.1.2 Effect of Light Intensity for Time of Deposition 60 Second	43-47
	4.1.2.1 Deposition at Light Intensity 3500±100 LUX	43
	4.1.2.2 Deposition atLight Intensity 2400±100 LUX	44
	4.1.2.3 Deposition at Light Intensity 1800±100 LUX	45
	4.1.2.4 Deposition at Light Intensity 450±100 LUX	46
	4.1.2.5 Deposition at Light Intensity 0 LUX (Dark)	47
	4.1.3 Effect of Light Intensity for Time of Deposition 60 Second	48-51
	4.1.3.1 Deposition at Light Intensity 3500±100 LUX	48
	4.1.3.2 Deposition at Light Intensity 2400±100 LUX	49
	4.1.3.3 Deposition at Light Intensity 1800±100 LUX	50
	4.1.3.4 Deposition at Light Intensity 450±100 LUX	51
	4.1.3.5 Deposition at Light Intensity 0 LUX(Dark)	51
	4.2Mechanism for Suppressed Depositionunder Light Condition	52
	4.3 Experimental Proof	53
	4.4.1Deposition without Reducing Agent	53
	4.4.2 Initial Stage of Deposition	54
	4.4Observation	55
	4.4.1 Elemental Analysis from EDS Data	56
	4.4.2 Surface Morphology from SEM Image	58

	4.4.3 Summery of Elemental Analysis and Surface Morphology	59
5.	Conclusion and Future work	61
	5.1 Conclusion	61
	5.2 Future Work	61
Refe	rences 62-60	į

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LIST OF TABLES

Table 1.1 Weight percentages of elements in earth's crust, applicable for PV	8
Table 3.1 Experimental Procedure for Alkaline Bath	40
Table 4.1 EDS Observation Table of Weight percentage	56
Table 4.2 Summery of Nickel Phosphorus from EDS data	58
Table 4.3 Surface morphology from SEM image	59
Table 4.4 Criteria for Quality of deposition	59
Table 4.5 Table for Quality of deposition	59

LIST OF FIGURES

Figure 1.1	Annual Production of Oil	2
Figure 1.2 Figure 1.3 Figure 1.4 Figure 2.1	Solar Radiation curve Market share of solar cell types sold during 2006 Different losses of solar cell Working of p-n junction solar cell	3 5 7 13
Figure 2.2	(a) Equivalent circuit of solar cell (b) I-V and P-V characteristics	14
Figure 2.3	Series resistance in a simple c-Si wafer based solar cell	16
Figure 2.4	(a) Magnified image of a screen used for printing the front contact	
	ofaSolar cell, (b) Front view of a completed screen printed	
	multicrystallineSi- solar cell	18
Figure 2.5	The Screen-printing process: (1) the openings in the screen are filled	
	WithPaste;(2) the squeegee brings the screen in intimate contact with	
	The Substrateand presses paste through the openings (3)while the	
	screen isLiftedUp, paste is released from the screen and sticks	
	to the substrate	19
Figure 2.6	SEM image of the Ag-Si interface of a thick-film finger on [100]	
	OrientedSi and the re-grown Ag crystallites	20
Figure 2.7	Different possible current transport mechanisms from Si emitter	
	to theAg grid	20
Figure 2.8	Schematic diagram of the laser micro-sintering process	21
Figure 2.9	SEM image (cross-section view) of a silicon solar cell, with	
	a laser micro-sintered silver contact and subsequently silver	
	platedcontact	22
Figure 2.10	Schematic of the light induced electroplating process	24
Figure 2.11	SEM images of the Ni/Cu contact system for high efficiencysolar cells: (a electroless plated Ni layer and (b) electroplated)
	Cu on a Ni layer	25

Figure 2.12	SEM images of plated Ni films (a) before and (b) after annealing		
	at 600°C for 30s	27	
Figure 2.13	Diagrammatic representation of an electron-beam evaporation system	30	
Figure 2.14	Printing head of the metal aerosol printing technique	32	
Figure 2.15	(A) Setup for reducing photoelectric effect of Nickel bath [40] (B)		
	Conventional Nickel bath	33	
Figure 2.16	Experimental Setup for electroless deposition	34	
Figure 3.1	Cutting and wrapping of the cell	36	
Figure 3.2	Etching the ARC with 49% HF	37	
Figure 3.3	lay out experimental setup for light condition	38	
Figure 3.4	(A) Actual experimental setup for light condition		
	(B) Distance betweenSampleand light source	38	
Figure3.5	Setup for Dark condition	39	
Figure 4.1SE	M image of textured Si wafer (sample) without deposition 42		
Figure 4.2	Energy dispersive spectroscopy of the textured Si substrate	42	
Figure 4.3	SEM image of the nickel deposited sample for 3500±100 LUX		
	Condition	43	
Figure 4.4	EDS of the nickel deposited sample for 3500±100 LUX condition	44	
Figure 4.5	SEM image of the nickel deposited sample for 2400±100 LUX		
	Condition	44	
Figure 4.6	EDS of the nickel deposited sample for 2400±100 LUX condition	45	
Figure 4.7	SEM image of nickel deposited sample for 1800±100 lux luminous		
	Intensity	45	
Figure 4.8	EDS of nickel deposited sample for 1800±100 lux luminous intensity	46	
Figure 4.9	SEM image of nickel deposited sample for ambient light condition		
Figure 4.10	EDS of nickel deposited sample for ambient light condition	47	
Figure 4.11	SEM image of nickel deposited sample under dark condition	47	
Figure 4.12	EDS of nickel deposited samples under dark condition	48	
Figure 4.13	SEM image of nickel deposited sample for 3500±100 lux luminous		
3	Intensity	48	
	,	.0	

Figure 4.14	EDS of nickel deposited samples under 3500±100 Condition	49
Figure 4.15	SEM image of the nickel deposited sample for 2400±100 LUX	
	Condition	49
Figure 4.16	EDS of the nickel deposited sample for 2400±100 LUX condition	50
Figure 4.17	SEM image of nickel deposited sample for 1800±100 lux luminous	
	Intensity	50
Figure 4.18	EDS of nickel deposited sample for 1800±100 lux luminous intensity	50
Figure 4.19	SEM image of nickel deposited sample for ambient light condition	51
Figure 4.20	EDX of nickel deposited sample for ambient light condition	51
Figure 4.21	SEM image of nickel deposited sample under dark condition	52
Figure 4.22	EDX of nickel deposited samples under dark condition	52
Figure 4.23	Mechanism; why deposition suppressed under light condition	53
Figure 4.24	Mechanism of deposition under dark condition	53
Figure 4.25	SEM image (Surface Morphology) deposition without using reducing	
	Agent	54
Figure 4.26	SEM image (Cross-section) deposition without using reducing agent	54
Figure 4.27	SEM image; Initial Stage of Deposition for 30 second	
	(A) Under 3500±200 LUX (B)Under Dark condition	55
Figure 4.28	Weight % of Ni Vs. light Intensity	57
Figure4.29	Weight % of P Vs. light Intensity	57

NOMENCLATURE

A Area

Ag Silver

Al Aluminum
AM Air mass

Ar Argon

ARC Anti-reflective coating

Au Gold B Boron

BSF Back Surface Field

CIGS Copper-indium-gallium-Selenite

Cl Chlorine

C₆H₇N₃O₇ Triammonium Citrate

CO₂ Carbon dioxide

Cu Copper

Cu₂SO₄ Copper Sulphate c-Si Crystalline Silicon CZ Czochralski Silicon

DI Deionized Water

EBE Electron Beam Evaporation

EDX Energy Dispersive Spectroscopy

EN Electroless Nickel Plating

ESCA Electron Spectroscopy for Chemical Analysis

FF Fill Factor
FZ Float Zone

GaAs Gallium Arsenide

GW Giga Watt

GIXRD Grazing Incidence Angle X-Ray Diffraction

HF Hydrofluoric acid H₂SO₄ Sulphuric Acid

H₂O₂ Hydrogen Peroxide

ICP-MS Inductively Coupled Plasma Molecular Spectroscopy

ICDD International Committee on Diffraction Data

InGaP Indium Gallium Phosphide

LIP Light Induced Plating NH_4Cl Ammonium Chloride NH_4OH Ammonium Hydroxide

NdYAG Neodymium Yttrium Aluminum Garnet Laser

NaH₂PO₂ Sodium Hypophosphite

NaOH Sodium Hydroxide

NIST National Institute of Standards and Technology

Ni Nickel

 $NiCl_2$ Nickel Chloride Ni_3P Nickel Phosphide NiSi Nickel Silicide Ni_3Si_2 Nickel Silicide Ni_5Si_2 Nickel Silicide

OPEC Organization of the Petroleum Exporting Countries

P Phosphorus
Pd Palladium

PdCl₂ Palladium Chloride

PECVD Plasma Enhanced Chemical Vapor Deposition

PESC Passivated Emitter Solar Cell

PERL Passivated Emitter Rear Locally Diffused Solar Cell

PV Photovoltaic

PVD Physical Vapor Deposition

R Resistance

SCR Space Charge Region

SEM Scanning Electron Microscope

Si Silicon

 SiO_2 Silicon Dioxide S_xN_y Silicon Nitride

SP Screen Printing

SPV Solar Photovoltaic

SRV Surface Recombination Velocities

STC Standard Test Conditions

Ti Titanium

TLM Transmission Line Model/Transfer Length Method

W Tungsten

Xe Xenon

XPS X-Ray Photoelectron Spectroscopy

XRD X-Ray Diffraction